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OCT 19 2001

Sheet 1 of 3

FORM PTO-1449 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE  
STATEMENT BY APPLICANT  
(37 CFR 1.98(b))Attorney Docket No.: L&L-I0078  
Applic. No. 09/939,330Applicant  
Alfred Kersch et al.Filing Date  
August 24, 2001  
Group Art Unit

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
	B						
	C						
	D						
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## FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES   NO
EF	J	03 197 394 A	08/28/91	Japan			X
EF	K	04 137 532 A	05/12/92	Japan			X
	L						
	M						
	N						

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EF	O	J.L. Archer et al.: "Chemical Vapor Deposition Of Single-Crystal Metal Oxides. II. Encapsulation Of Polycrystalline Conductors In Single-Crystal Ferrite", J. Phys. Chem. Solids, Suppl. 1967, No. 1, pp. 337-340
EF	P	Jing Zhao et al.: "Low Pressure Organometallic Chemical Vapor Deposition Of High -T <sub>C</sub> Superconducting YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-δ</sub> Films", Solid State Communications, Vol. 69, No. 2, 1989, pp. 187-189

EXAMINER <i>G. Kersch</i>	DATE CONSIDERED 12/14/02
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609;  
 Draw line through citation if not in conformance and not considered. Include copy of this form with  
 next communication to applicant.



Sheet 2 of 3

FORM PTO-149 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT  
(37 CFR 1.98(b))

Attorney Docket No.: L&L-10078  
Applic. No. 09/939,330

Applicant Alfred Kersch et al.

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### OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EF	O	Shogo Matsubara et al.: "Preparation of epitaxial ABO <sub>3</sub> perovskite-type oxide thin films on a (100)MgAl <sub>2</sub> O <sub>4</sub> /Si substrate", J. Appl. Phys. Vol. 66, No. 12, December 15, 1989, pp. 5826-5832
EF	P	Clive D. Chandler et al.: "Chemical Aspects of Solution Routes to Perovskite-Phase Mixed-Metal Oxides from Metal-Organic Precursors", Chem. Rev. 1993, No. 93, pp. 1205-1241

EXAMINER	DATE CONSIDERED
<i>E. Fink</i>	12/14/02

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FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))	Attorney Docket No.: L&L-10078 Applic. No. 09/939,330  Applicant Alfred Kersch et al.  Filing Date August 24, 2001 Group Art Unit
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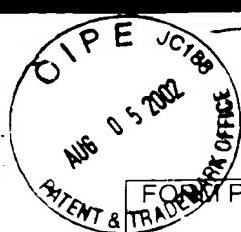
## FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES   NO
	J						
	K						
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	M						
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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EF	O	D. Saulys et al.: "An examination of the surface decomposition chemistry of lithium niobate precursors under high vacuum conditions", Journal of Crystal Growth, No. 217, 2000, pp. 287-301
EF	P	Y. Gao et al.: "Effects of precursors and substrate materials on microstructure, dielectric properties, and step coverage of (Ba,Sr)TiO <sub>3</sub> films grown by metalorganic vapor deposition", Journal of Applied Physics, Vol. 87, No. 1, January 1, 2000, pp. 124-132

EXAMINER <i>E. Kersch</i>	DATE CONSIDERED 12/14/02
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Attorney Docket No.: L&L-I0078  
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09/939,330

Applicant  
Alfred Kersch et al.

Filing Date  
August 24, 2001  
Group Art Unit  
1763

### U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
EF	A	5,399,387	03/21/95	Law et al.			
EF	B	5,508,067	04/16/96	Sato et al.			
	C						
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### FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES   NO
EF	J	0 296 891 A2	12/28/88	Europe			X
	K						
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